

Electronic Acknowledgement Receipt

EFS ID:	1309064
Application Number:	09824936
International Application Number:	
Confirmation Number:	9938
Title of Invention:	Plasma reactor for the treatment of large size substrates
First Named Inventor/Applicant Name:	Jacques Schmitt
Customer Number:	21706
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Filer Authorized By:	Peter C. Michalos
Attorney Docket Number:	H37-091 DIV
Receipt Date:	13-NOV-2006
Filing Date:	03-APR-2001
Time Stamp:	14:58:27
Application Type:	Utility

Payment information:

Submitted with Payment	no
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File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1	Appeal Brief Filed	H37-091DIV-Appeal-Brief-FILED.pdf	89420	no	20

Warnings:

Information:					
2	Fee Worksheet (PTO-875)	fee-info.pdf	8162	no	2
Warnings:					
Information:					
Total Files Size (in bytes):					97582
<p>This Acknowledgement Receipt evidences receipt on the noted date by the USPTO of the indicated documents, characterized by the applicant, and including page counts, where applicable. It serves as evidence of receipt similar to a Post Card, as described in MPEP 503.</p> <p>New Applications Under 35 U.S.C. 111 If a new application is being filed and the application includes the necessary components for a filing date (see 37 CFR 1.53(b)-(d) and MPEP 506), a Filing Receipt (37 CFR 1.54) will be issued in due course and the date shown on this Acknowledgement Receipt will establish the filing date of the application.</p> <p>National Stage of an International Application under 35 U.S.C. 371 If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.</p>					